

ELEG 646 - Spring 09
Electronic Device Principles
Final Examination

20 May 2010

NAME _____

Time Limit: 120 minutes

Closed Books and Notes. You may use your own calculator, but may not loan or borrow one (ask proctor if you have questions). Put expression in a final form as best you can.

Guidelines:

- I. Full credit requires the final dimensions/ units for all numerical quantities that you calculate.
- II. Show all work and calculations for full credit; accuracy to 2 significant figures is sufficient.
- III. Assume that the material is silicon at room temperature (300 K), unless otherwise stated.
- IV. At 300K temperature; thermal energy $k_B T = 0.026 eV$, silicon intrinsic concentration $n_i = 1 \times 10^{10} \text{ cm}^{-3}$, recombination lifetimes: $\tau_n, \tau_p = 1 \text{ } \mu\text{sec}$; dielectric constant $\kappa_{Si} = 11.8$;

In general; permittivity of free space $\epsilon_0 = 8.85 \times 10^{-14} \text{ F/cm}$; electron charge $|q| = 1.6 \times 10^{-19} \text{ Coul}$;

V. Equations:

$$p_{op} = i\hbar d/dx \quad f_{FD}(E) = 1/[1 + \exp(E-E_F)/k_B T] \quad E = Q V$$

$$n = n_i \exp[(E_F - E_i)/k_B T]. \quad p = n_i \exp[(E_i - E_F)/k_B T] \quad n_o p_o = n_i^2 \quad np = n_i^2 e^{(F_n - F_p)/k_B T}$$

$$n = N_C \exp[-(E_C - E_F)/k_B T] \quad N_C = 2.8 \times 10^{19} \text{ cm}^{-3} \quad p = N_V \exp[-(E_F - E_V)/k_B T] \quad N_V = 1.04 \times 10^{19} \text{ cm}^{-3}$$

$$J_n = q\mu_n n \mathcal{E} + qD_n dn/dx \quad J_p = q\mu_p p \mathcal{E} - qD_p dp/dx \quad \sigma_{elec} = q(n\mu_n + p\mu_p)$$

$$U_n = (n_p - n_{po})/\tau_n \quad U_p = (p_n - p_{no})/\tau_p \quad p' = p - p_o = g_{opt} \tau_p \quad n' = n - n_o = g_{opt} \tau_n$$

$$C_{dep} = \kappa_s \epsilon_0 A/W \quad C_{diff} = qI\tau/k_B T \quad D/\mu = k_B T/q \quad L = \sqrt{D\tau}$$

$$\partial p/\partial t = -1/q \partial J_p/\partial x - p'/\tau_p \quad \partial n/\partial t = -1/q \partial J_n/\partial x - n'/\tau_n ;$$

$$\partial p/\partial t = D_p \partial^2 p/\partial x^2 - p'/\tau_p \quad \partial n/\partial t = D_n \partial^2 n/\partial x^2 - n'/\tau_n$$

$$\phi_{bi} = k_B T/q \ln(N_A N_D/n_i^2) \quad \phi = (E_F - E_i)/q + \phi_{ref} (\phi_{ref} = \text{constant or }) ; \quad \mathcal{E} = -d\phi/dx$$

$$I = qA(D_p p_n/L_p + D_n n_p/L_n)[e^{qV/kT} - 1] = I_o[e^{qV/kT} - 1]; \quad W_{dep} = [(2\kappa_s \epsilon_0/q)(1/N_A + 1/N_D)(\phi_{bi} - V_F)]^{1/2}$$

$$\mathcal{E}_{max} = 2(\phi_{bi} - V_F)/W_{dep} \quad p_n(x_{no}) = p_{no}(x_{no})e^{qV_f/kT} ; \quad n_p(-x_{po}) = n_{po}(-x_{po})e^{qV_f/kT}$$

VI. Equations: (note, kT , ϵ are on page 1)

$$n = n_i \exp[(E_F - E_i)/k_B T].$$

$$p = n_i \exp[(E_i - E_F)/k_B T]$$

$$J_n = q\mu_n n \mathcal{E} + qD_n dn/dx$$

$$J_p = q\mu_p p \mathcal{E} - qD_p dp/dx$$

$$U_n = (n_p - n_{p0})/\tau_n$$

$$U_p = (p_n - p_{n0})/\tau_p$$

$$C = \epsilon_s / W$$

One-sided step junction:

$$C = \epsilon_s / W; \quad \phi_{bi} = (k_B T/q) \ln[N_A N_D / n_i^2]$$

Breakdown (for n^+ -p diode)

$$\mathcal{E}_{max} = [2qN_A |V_R| / \epsilon_s]^{1/2}; \quad BV = \epsilon_s \mathcal{E}_{crit}^2 / 2qN_A$$

Schottky junctions:

$$I_F = A_J A^* T^2 \exp(-q\phi_B/kT) [\exp(qV/\eta kT) - 1]; \text{ where } \eta = \text{ideality factor}$$

pnp transistors:

$$I_E = I_C + I_B;$$

$$I_C = \alpha_F I_E + I_{CBO}$$

$$I_C = \beta I_B + I_{CEO}$$

$$\alpha_F = \gamma \alpha_T M$$

$$I_{pE} = A_E q^2 n_i^2 D_p / Q_{B0} \exp[(qV_{BE})/k_B T]$$

$$Q_{B0} = q \int_0^{WB} N_D(x) dx = q GN; \text{ (GN = Gummel number)}$$

$$\alpha_F = \gamma \alpha_T M$$

Ebers-Moll model (for pnp):

$$I_E = I_{ES}/p_{no}(\Delta p_E - \alpha_F \Delta p_C);$$

$$I_C = I_{CS}/p_{no}(\alpha_R \Delta p_E - \Delta p_C)$$

$$\Delta p_E = p_{no}(e^{qV_{EB}/kT} - 1)$$

$$\Delta p_C = p_{no}(e^{qV_{CB}/kT} - 1)$$

$$\text{Reciprocity: } \alpha_F I_{ES} = \alpha_R I_{CS} = I_S$$

Junction Field Effect Transistors:

$$pFET: V_P = qN_A a^2 / 2\epsilon_s \text{ or}$$

$$nFET: V_P = qN_D a^2 / 2\epsilon_s$$

$$\phi_{bi} = (k_B T/q) \ln(N_A N_D / n_i^2)$$

$$\text{cutoff frequency: } f_T = g_m / 2\pi C_{GS}$$

Notes:

$$C_B = \text{doping concentration in the bulk} \equiv N_A \text{ or } N_D$$

$$\phi_B = \phi_{bi} = \text{built-in voltage (contact potential)}$$

$$A_J = \text{junction area}$$

TABLE 4.2
IMPORTANT FORMULAS IN SEMICONDUCTOR PHYSICS
 Complete ionization of impurities
 Thermal equilibrium

| | |
|--|--|
| Charge neutrality | $\rho = q(p - n + N_D - N_A) = 0$ |
| Equilibrium condition | $pn = n_i^2$ |
| Fermi-Dirac distribution function | $f(E) = \frac{1}{1 + e^{(E-E_F)/kT}}$ |
| Carrier concentrations in non-degenerate semiconductors: | $n = N_c e^{-(E_c-E_F)/kT} = n_i e^{(E_F-E_i)/kT}$ $p = N_v e^{-(E_F-E_v)/kT} = n_i e^{(E_i-E_F)/kT}$ |
| In the extrinsic case, $ N_D - N_A \gg n_i$: | $n_n \doteq N_D - N_A$ $p_p \doteq N_A - N_D$ $p_n \doteq \frac{n_i^2}{N_D - N_A}$ $n_p \doteq \frac{n_i^2}{N_A - N_D}$ |

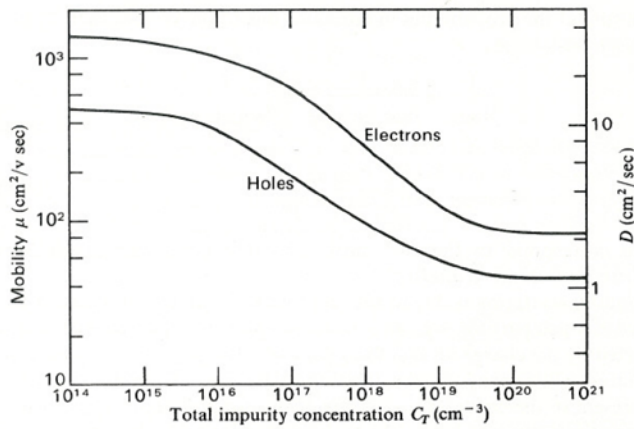


Fig. 4.11 The effect of the total ionized impurity concentration on the mobility of carriers in silicon at room temperature.⁴ Also shown are the corresponding values of diffusivity.

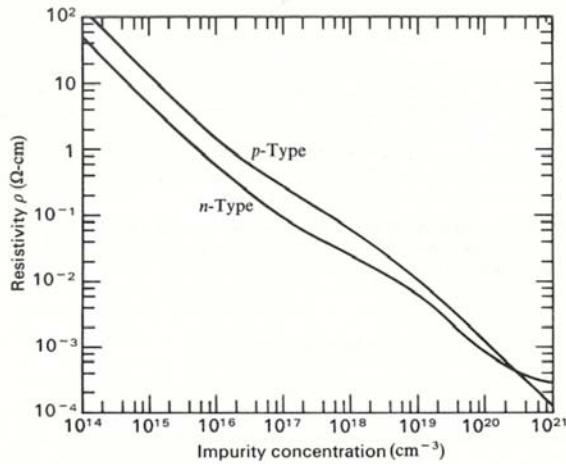


Fig. 4.14 Resistivity of silicon at room temperature as a function of acceptor or donor impurity concentration.⁶

TABLE 3.1 Schottky Barriers to Silicon [10]
 ($q\chi$ for Silicon = 4.05 eV)

| Silicon Type | Metal | $q\Phi_M$ (eV) | $q\phi_B$ (eV) |
|--------------|-------|----------------|----------------|
| <i>n</i> | Al | 4.1 | 0.69 |
| <i>p</i> | Al | — | 0.38 |
| <i>n</i> | Pt | 5.3 | 0.85 |
| <i>p</i> | Pt | — | 0.25 |
| <i>n</i> | W | 4.5 | 0.65 |
| <i>n</i> | Au | 4.75 | 0.79 |
| <i>p</i> | Au | — | 0.25 |

TABLE 6.1
IMPORTANT FORMULAS FOR ONE-SIDED STEP JUNCTIONS

| | |
|-----------------------------|---|
| Built-in voltage | $\phi_B \cong 2 \frac{kT}{q} \ln \frac{C_B}{n_i}$ |
| Depletion region width | $W = \sqrt{\frac{2K_s \epsilon_0 [\phi_B \pm V_J]}{qC_B}}$ where $\begin{cases} +: \text{ reverse} \\ -: \text{ forward} \end{cases}$ bias |
| Maximum electric field | $\epsilon_{\max} = 2 \frac{\phi_B \pm V_J }{W}$ |
| Capacitance per unit area | $C = \frac{K_s \epsilon_0}{W}$ |
| Reverse current | $I_R = I_{\text{gen}} + I_{\text{diff}}$ $I_{\text{gen}} = \frac{1}{2} q \frac{n_i}{\tau} W A_J$ $I_{\text{diff}} = qD \frac{n_i^2}{C_{BL}} A_J$ |
| Forward current | $I_F = I_{\text{rec}} + I_{\text{diff}}$ $I_{\text{rec}} = -\frac{1}{2} q \frac{n_i}{\tau} W e^{q V_F /2kT} A_J$ $I_{\text{diff}} = -qD \frac{n_i^2}{C_{BL}} e^{q V_F /kT} A_J$ |
| Avalanche breakdown voltage | $BV = \frac{K_s \epsilon_0 e \epsilon_{\text{crit}}^2}{2qC_B}$ |

TABLE 7.1
IMPORTANT FORMULAS FOR JUNCTION TRANSISTORS

| | pnp | npn |
|--------------------|---|---|
| Current gain | $\alpha \cong h_{FB} \equiv \frac{I_C}{I_E} \quad \beta \cong h_{FE} \equiv \frac{I_C}{I_B} \quad \beta = \frac{\alpha}{1 - \alpha}$ $\alpha = \gamma \alpha_T$ [See footnote on page 219.] | |
| Transport factor | $\alpha_T \cong 1 - \frac{1}{2} \left(\frac{W_B}{L_{pB}} \right)^2$ $\cong 1 - \frac{t_{tr}}{\tau_p}$ | $\alpha_T \cong 1 - \frac{1}{2} \left(\frac{W_B}{L_{nB}} \right)^2$ $\cong 1 - \frac{t_{tr}}{\tau_n}$ |
| Emitter efficiency | $\gamma = \frac{1}{1 + \frac{B}{E} + \frac{1}{2} \sqrt{\frac{qBA_J}{I_C}} R}$ $R = \frac{W_{EB}}{\tau_0} + s_0 \frac{A_e}{A_J}$ $B \equiv \frac{N_{DB}W_B}{D_{pB}} \quad E \equiv \frac{N_{AE}W_E}{D_{nE}}$ | |
| Transit time | $t_{tr} = \frac{W_B^2}{2D_{pB}}$ | $t_{tr} = \frac{W_B^2}{2D_{nB}}$ |
| Base resistance | $r_B' = \frac{1}{12} \frac{\rho_B}{W_B} \frac{L}{Z}$ for stripe geometry | |
| Leakage currents | $I_{CEO} = \frac{I_{CBO} M}{1 - \gamma \alpha_T M}$ | |
| Maximum voltages | $BV_{CEO} \cong \frac{BV_{CBO}}{\sqrt[3]{h_{FE}}}$ | |
| Minimum voltage | $V_{CE}(\text{sat}) = \pm \left(\frac{kT}{q} \left \ln \frac{\alpha_R \left[1 - \frac{I_C}{I_B h_{FE}} \right]}{1 + \frac{I_C (1 - \alpha_R)}{I_B}} \right + I_E r_{SE} + I_C r_{SC} \right)$ -pnp +npn | |

note for Table 8.1, $d = 2a$ (full channel thickness) the symbol ϕ_B is the magnitude of built in voltage

TABLE 8.1
IMPORTANT FORMULAS FOR JUNCTION FIELD-EFFECT TRANSISTORS

| | <i>n</i> -channel $V_D > 0, V_G < 0; I_D$ flows from drain to source | <i>p</i> -channel $V_D < 0, V_G > 0; I_D$ flows from source to drain |
|--|--|--|
| Current-voltage characteristics | $I_D = G_o \left\{ V_D - \frac{2}{3\sqrt{8K_s\epsilon_0}} \sqrt{qN_D d^2} \right. \\ \left. \times [(V_D + \phi_B - V_G)^{3/2} - (\phi_B - V_G)^{3/2}] \right\}$ <p>where $G_o \equiv \frac{Z}{L} q\mu_n N_D d$</p> | $I_D = G_o \left\{ -V_D - \frac{2}{3\sqrt{8K_s\epsilon_0}} \sqrt{qN_A d^2} \right. \\ \left. \times [(V_G + \phi_B - V_D)^{3/2} - (V_G + \phi_B)^{3/2}] \right\}$ <p>where $G_o \equiv \frac{Z}{L} q\mu_p N_A d$</p> |
| Saturation voltage | $V_{Dsat} = \frac{qN_D d^2}{8K_s\epsilon_0} - \phi_B + V_G$ | $V_{Dsat} = -\frac{qN_A d^2}{8K_s\epsilon_0} + \phi_B + V_G$ |
| Turn-off voltage | $V_T = -\frac{qN_D d^2}{8K_s\epsilon_0} + \phi_B$ | $V_T = \frac{qN_A d^2}{8K_s\epsilon_0} - \phi_B$ |
| Conductance (linear region) Transconductance (saturation) | $\left. \begin{aligned} g_{linear} \\ g_{msat} \end{aligned} \right\} = G_o \left[1 - \sqrt{\frac{8K_s\epsilon_0(\phi_B - V_G)}{qN_D d^2}} \right]$ | $\left. \begin{aligned} g_{linear} \\ g_{msat} \end{aligned} \right\} = G_o \left[1 - \sqrt{\frac{8K_s\epsilon_0(\phi_B + V_G)}{qN_A d^2}} \right]$ |
| Saturation current | $I_{Dsat} = G_o \left\{ \left[\frac{2}{3\sqrt{8K_s\epsilon_0}} \sqrt{\frac{8K_s\epsilon_0(\phi_B - V_G)}{qN_D d^2}} - 1 \right] \right. \\ \left. \times (\phi_B - V_G) + \frac{1}{3} \frac{qN_D d^2}{8K_s\epsilon_0} \right\}$ | $I_{Dsat} = G_o \left\{ \left[\frac{2}{3\sqrt{8K_s\epsilon_0}} \sqrt{\frac{8K_s\epsilon_0(\phi_B + V_G)}{qN_A d^2}} - 1 \right] \right. \\ \left. \times (\phi_B + V_G) + \frac{1}{3} \frac{qN_A d^2}{8K_s\epsilon_0} \right\}$ |
| Maximum frequency | $f_o = \frac{g_m}{C_G} \leq \frac{q\mu_n N_D d^2}{2K_s\epsilon_0 L^2}$ | $f_o = \frac{g_m}{C_G} \leq \frac{q\mu_p N_A d^2}{2K_s\epsilon_0 L^2}$ |
| Effect of series resistances | <p>Linear region $g(\text{obs}) = \frac{g}{1 + (R_s + R_d)g}$</p> <p>Saturation region $g_{msat}(\text{obs}) = \frac{g_{msat}}{1 + R_s g_{msat}}$</p> | |

TABLE 8.3 Formulas for the Oxide-Silicon System

| <i>p</i> -type substrate (<i>n</i> -channel) | <i>n</i> -type substrate (<i>p</i> -channel) |
|--|---|
| Flat-band voltage (Equation 8.4.6) | |
| $V_{FB} = \Phi_{MS} - \frac{Q_f}{C_{ox}} - \frac{1}{C_{ox}} \int_0^{x_{ox}} \frac{x}{x_{ox}} \rho(x) dx$ | |
| Bulk potential (Equation 4.2.9) | |
| $\phi_p = -\frac{kT}{q} \ln\left(\frac{N_a}{n_i}\right)$ | $\phi_n = \frac{kT}{q} \ln\left(\frac{N_d}{n_i}\right)$ |
| Surface potential for strong inversion (Table 3.1) | |
| Thermal equilibrium $\phi_s = \phi_p $ | $\phi_s = - \phi_n $ |
| $\phi_s - \phi_p = 2 \phi_p $ | $\phi_s - \phi_n = -2 \phi_n $ |
| With bias $(V_C - V_B) = V_{CB}$ | |
| $\phi_s = \phi_p + V_{CB}$ | $\phi_s = - \phi_n - V_{CB} $ |
| Maximum depletion width, x_{dmax} (Equation 8.3.6) | |
| Thermal equilibrium | |
| $\sqrt{\frac{4\epsilon_s \phi_p }{qN_a}}$ | $\sqrt{\frac{4\epsilon_s \phi_n }{qN_d}}$ |
| With bias V_{CB} (Equation 8.3.8) | |
| $\sqrt{\frac{2\epsilon_s(2 \phi_p + V_{CB})}{qN_a}}$ | $\sqrt{\frac{2\epsilon_s(2 \phi_n + V_{CB})}{qN_d}}$ |
| Work-function difference, Φ_{MS} | |
| $\Phi_M - (X + E_g/2q + \phi_p)$ | $\Phi_M - (X + E_g/2q - \phi_n)$ |
| Threshold voltage V_T (arbitrary reference) (Equation 8.3.18) | |
| $V_{FB} + V_C + 2 \phi_p \\ + \frac{1}{C_{ox}} \sqrt{2\epsilon_s q N_a (2 \phi_p + V_C - V_B)}$ | $V_{FB} + V_C - 2 \phi_n \\ - \frac{1}{C_{ox}} \sqrt{2\epsilon_s q N_d (2 \phi_n + V_B - V_C)}$ |

TABLE 9.4 MOSFET Equations

| Basic Electrostatic Equations | |
|--|---|
| n-channel | p-channel |
| Depletion charge density at threshold (Equation 8.3.9) $Q_d = -qN_a x_{dmax} = -\sqrt{2\epsilon_s q N_a (2 \phi_p + V_{SB})}$ | $Q_d = +qN_a x_{dmax} = +\sqrt{2\epsilon_s q N_a (2 \phi_p + V_{SB})}$ |
| Flatband voltage (Equation 8.5.6) $V_{FB} = \Phi_{MS} - \frac{Q_f}{C_{ox}} - \frac{1}{C_{ox}} \int_0^{x_{ox}} \frac{x\rho(x)}{x_{ox}} dx$ | |
| Threshold voltage (Equation 8.3.18) $V_T = V_{FB} + V_S + 2 \phi_p + \frac{ Q_d }{C_{ox}}$ | $V_T = V_{FB} - V_S - 2 \phi_p - \frac{ Q_d }{C_{ox}}$ |
| Threshold-voltage shift with body bias (Equation 9.1.11) $\Delta V_T = \frac{\sqrt{2\epsilon_s q N_a}}{C_{ox}} (\sqrt{2 \phi_p + V_{SB} } - \sqrt{2 \phi_p })$ | $\Delta V_T = -\frac{\sqrt{2\epsilon_s q N_a}}{C_{ox}} (\sqrt{2 \phi_p + V_{SB} } - \sqrt{2 \phi_p })$ |
| Long-Channel Current-Voltage Equations | |
| Linear-region drain current (Equation 9.1.5) $I_D = \mu_n C_{ox} \frac{W}{L} \left[(V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right]$ | $I_D = -\mu_p C_{ox} \frac{W}{L} \left[(V_{GS} - V_T) V_{DS} - \frac{V_{DS}^2}{2} \right]$ |
| Long-channel saturation drain voltage $V_{Dsat} = (V_{GS} - V_T)$ | |
| Saturation-region drain current (Equation 9.1.6) $I_{Dsat} = \mu_n C_{ox} \frac{W}{2L} (V_{GS} - V_T)^2$ | $I_{Dsat} = -\mu_p C_{ox} \frac{W}{2L} (V_{GS} - V_T)^2$ |
| Channel-length modulation (Equation 9.1.10) $I_{Dsat} = \mu_n C_{ox} \frac{W}{2L} (V_{GS} - V_T)^2 \left(1 + \frac{V_{DS}}{V_A} \right)$ | $I_{Dsat} = -\mu_p C_{ox} \frac{W}{2L} (V_{GS} - V_T)^2 \left(1 - \frac{V_{DS}}{V_A} \right)$ |
| Saturation-region transconductance (Equation 9.1.37) $g_{msat} = \mu_n C_{ox} \frac{W}{L} (V_{GS} - V_T) = \frac{2I_{Dsat}}{(V_{GS} - V_T)}$ | $g_{msat} = -\mu_p C_{ox} \frac{W}{L} (V_{GS} - V_T) = -\frac{2I_{Dsat}}{(V_{GS} - V_T)}$ |
| Long-Channel Current-Voltage Equations with Substrate Charge | |
| Linear-region drain current (Equation 9.1.17) $I_D = \mu_n C_{ox} \frac{W}{L} \left[(V_{GS} - V_T) V_{DS} - \frac{\alpha V_{DS}^2}{2} \right]$ | $I_D = -\mu_p C_{ox} \frac{W}{L} \left[(V_{GS} - V_T) V_{DS} - \frac{\alpha V_{DS}^2}{2} \right]$ |
| Saturation drain voltage (Equation 9.1.18) $V_{Dsat} = \frac{(V_{GS} - V_T)}{\alpha}$ | |
| Saturation-region drain current (Equation 9.1.19) $I_{Dsat} = \mu_n C_{ox} \frac{W}{2\alpha L} (V_{GS} - V_T)^2$ | $I_{Dsat} = -\mu_p C_{ox} \frac{W}{2\alpha L} (V_{GS} - V_T)^2$ |
| Short-Channel Current-Voltage Equations | |
| Effective vertical field (Equation 9.2.3) $\mathcal{E}_{eff} = \frac{(V_{GS} - V_T)}{6x_{ox}} + \frac{(V_T + V_D)}{3x_{ox}}$ | $\mathcal{E}_{eff} = \frac{(V_{GS} - V_T)}{6x_{ox}} + \frac{(V_T - V_D)}{3x_{ox}}$ |
| Effective mobility (Equation 9.2.4) $\mu_{eff} = \frac{\mu_0}{1 + (\mathcal{E}_{eff}/\mathcal{E}_0)^{\gamma}}$ | $\mu_{eff} = \frac{\mu_0}{1 + (-\mathcal{E}_{eff}/\mathcal{E}_0)^{\gamma}}$ |
| Saturation \mathcal{E} -field (Equation 9.2.7) $\mathcal{E}_{sat} = 2v_{sat}/\mu_{eff}$ | $\mathcal{E}_{sat} = -2v_{sat}/\mu_{eff}$ |
| Linear-region drain current (Equation 9.2.9) $I_D = \mu_{eff} C_{ox} \frac{W}{L} \left[(V_{GS} - V_T) - \frac{V_{DS}}{2} \right] \frac{V_{DS}}{1 + (V_{DS}/\mathcal{E}_{sat}L)}$ | $I_D = -\mu_{eff} C_{ox} \frac{W}{L} \left[(V_{GS} - V_T) - \frac{V_{DS}}{2} \right] \frac{V_{DS}}{1 + (V_{DS}/\mathcal{E}_{sat}L)}$ |
| Saturation drain voltage (Equation 9.2.11) $V_{Dsat} = \frac{(V_{GS} - V_T)\mathcal{E}_{sat}L}{V_{GS} - V_T + \mathcal{E}_{sat}L}$ | |
| Saturation-region drain current (Equation 9.2.10) $I_{Dsat} = WC_{ox}v_{sat}(V_{GS} - V_T - V_{Dsat})$ | $I_{Dsat} = -WC_{ox}v_{sat}(V_{GS} - V_T - V_{Dsat})$ |

TABLE 1.3 Properties of Semiconductors and Insulators (at 300 K Unless Otherwise Noted)

| Property | Symbol | Units | Si | Ge | GaAs | GaP | SiO ₂ | Si ₃ N ₄ |
|---|-----------------------|-------------------------------------|-----------------------|-----------------------|-----------------------|-----------------------|--------------------------------------|--------------------------------|
| Crystal structure | | | Diamond | Diamond | Zincblende | Zincblende | [Amorphous for most IC applications] | |
| Atoms per unit cell | | | 8 | 8 | 8 | 8 | | |
| Atomic number | Z | | 14 | 32 | 31/33 | 31/15 | 14/8 | 14/7 |
| Atomic or molecular weight | MW | g/g-mole | 28.09 | 72.59 | 144.64 | 100.70 | 60.08 | 140.28 |
| Lattice constant | a_0 | nm | 0.54307 | 0.56575 | 0.56532 | 0.54505 | | 0.775 |
| Atomic or molecular density | N_0 | cm ⁻³ | 5.00×10^{22} | 4.42×10^{22} | 2.21×10^{22} | 2.47×10^{22} | 2.20×10^{22} | 1.48×10^{22} |
| Density | | g cm ⁻³ | 2.328 | 5.323 | 5.316 | 4.13 | 2.19 | 3.44 |
| Energy gap 300K | E_g | eV | 1.124 | 0.67 | 1.42 | 2.24 | -8 to 9 | 4.7 |
| OK | E_g | eV | 1.170 | 0.744 | 1.52 | 2.40 | | |
| Temperature dependence | $\Delta E_g/\Delta T$ | eV K ⁻¹ | -2.7×10^{-4} | -3.7×10^{-4} | -5.0×10^{-4} | -5.4×10^{-4} | | |
| Relative permittivity | ϵ_r | | 11.7 | 16.0 | 13.1 | 10.2 | 3.9 | 7.5 |
| Index of refraction | n | | 3.44 | 3.97 | 3.3 | 3.3 | 1.46 | 2.0 |
| Melting point | T_m | °C | 1412 | 937 | 1237 | 1467 | ~1700 | ~1900 |
| Vapor pressure | | Torr (mm Hg) | 10^{-7} (1050) | 10^{-9} (750) | 1 (1050) | 10^{-6} (770) | | |
| | | (at °C) | 10^{-5} (1250) | 10^{-7} (880) | 100 (1220) | 10^{-4} (920) | | |
| Specific heat | C_p | J (g K) ⁻¹ | 0.70 | 0.32 | 0.35 | | 1.4 | 0.17 |
| Thermal conductivity | κ | W(cm K) ⁻¹ | 1.412 | 0.606 | 0.455 | 0.97 | 0.014 | 0.185(?) |
| Thermal diffusivity | D_{th} | cm ² s ⁻¹ | 0.87 | 0.36 | 0.44 | | 0.004 | 0.32(?) |
| Coefficient of linear thermal expansion | α' | K ⁻¹ | 2.5×10^{-6} | 5.7×10^{-6} | 5.9×10^{-6} | 5.3×10^{-6} | 5×10^{-7} | 2.8×10^{-6} |
| Intrinsic carrier concentration* | n_i | cm ⁻³ | 1.45×10^{10} | 2.4×10^{13} | 9.0×10^6 | | | |
| Lattice mobility | | | | | | | | |
| Electron | μ_n | cm ² (V s) ⁻¹ | 1417 | 3900 | 8800 | 300 | 20 | |
| Hole | μ_p | cm ² (V s) ⁻¹ | 471 | 1900 | 400 | 100 | ~10 ⁻⁸ | |
| Effective density of states | | | | | | | | |
| Conduction band | N_c | cm ⁻³ | 2.8×10^{19} | 1.04×10^{19} | 4.7×10^{17} | | | |
| Valence band | N_v | cm ⁻³ | 1.04×10^{19} | 6.0×10^{18} | 7.0×10^{18} | | | |
| Electric field at breakdown | \mathcal{E}_1 | V cm ⁻¹ | 3×10^6 | 8×10^4 | 3.5×10^5 | | $6 - 9 \times 10^6$ | |
| Effective mass | | | | | | | | |
| Electron | m_n^*/m_0 | | 1.08 ^a | 0.55 ^a | 0.068 | 0.5 | | |
| | | | 0.26 ^b | 0.12 ^b | | | | |
| Hole | m_p^*/m_0 | | 0.81 ^a | 0.3 | 0.5 | 0.5 | | |
| | | | 0.386 ^b | | | | | |
| Electron affinity | χ | eV | 4.05 | 4.00 | 4.07 | ~4.3 | 1.0 | |
| Average energy loss per phonon scattering | | eV | 0.063 | 0.037 | 0.035 | | | |
| Optical phonon mean-free path | | | | | | | | |
| Electron | λ_{ph} | nm | 6.2 | 6.5 | 3.5 | | | |
| Hole | λ_{ph} | nm | 4.5 | 6.5 | 3.5 | | | |